

<b>Notice of References Cited</b>	Application/Control No. 10/786,290	Applicant(s)/Patent Under Reexamination FUJIMOTO ET AL	
	Examiner Anita K. Alanko	Art Unit 1765	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
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	L	US-			
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**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	JP 2002287377 A	10-2002	Japan	SAITO et al.	
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Park, M. et al "Block Copolymer Lithography: Periodic Arrays of 10exp11 Holes in 1 Square Centimeter" Science, 30 May 1997, Vol.276, 1401-4.
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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